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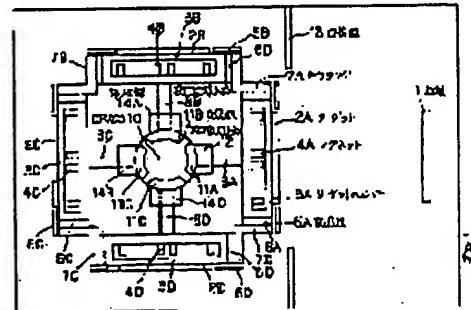
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(54) APPARATUS FOR PRODUCTION OF LAMINATED STRUCTURAL THIN FILM AND MOTION INTRODUCING DEVICE

(57)Abstract:

PURPOSE: To prevent the intrusion of the sputtered particles, etc., from the gases released from a vacuum chamber and other targets as impurities into films and to increase the degree of freedom in position control of a substrate in this vacuum chamber.

CONSTITUTION: Plural sputtering sources 2A to 2D mounted with magnetron sputtering electrodes are disposed in parallel around a revolving shaft 10 of a swiveling means and electric power for sputtering is impressed to one of the electrodes. The other electrodes are grounded. Members which can make rotational, linear and oscillatory motions are constituted as the motion introducing device of the vacuum device and a chucking mechanism for converting the above-mentioned linear motion to the holding operation of the substrate 1 is constituted.



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